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L2	1	L1 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:38
L3	<b>7</b>	embroidery and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT;	OR	OFF	2004/04/29 11:37
L4	2	L3 and @ad<"20010223"	IBM_TDB US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:40
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L15	512	L14 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 12:11
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L17	294	L16 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 12:11
S35	6	embroidery and design and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 06:55
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